

## **Brian DeVries**

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### **Education**

Bachelor of Arts, Physics, Luther College, Decorah, IA.  
Master of Science, Physics, Arizona State University, Phoenix, AZ.  
Master of Science, Technology Management, University of St. Thomas, St. Paul, MN.



### **Professional Experience**

Began as a Research Physicist using Synchrotron and UHV material analysis techniques. While studying at ASU he used Synchrotron X-ray diffraction, RHEED, LEED and Auger analysis to study semiconductor surface interfaces. In addition, Brian developed an electron beam thin metal film evaporator used to deposit controlled sub-monolayer films on semiconductors. After receiving his Masters in Physics, Brian pursued material analysis with X-ray Absorption Spectroscopy. Materials studied ranged from reactive catalysts, polymers, metals, and environmental samples.

After many years of X-ray materials research, Brian applied his physics background to the field of thin film metrology development. He worked for many years in developing and refining thin film measurements for the disc drive industry. Techniques included Remnant Flux, B-H Loop, X-ray, and other materials characterization methods. Calibration techniques were refined to improve process control and device yield.

Brian returned to school and received a Masters in Technology Management from the University of St. Thomas in 2004. Since then Brian has managed metrology laboratories in the Midwest, the East and West Coasts, Florida, and serves as a Metrology Ambassador for the National Conference of Standards Laboratories International.

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